

Shiyuan Liu

List of Publications by Year in descending order

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198
papers

3,514
citations

186265

28
h-index

189892

50
g-index

199
all docs

199
docs citations

199
times ranked

3743
citing authors

#	ARTICLE	IF	CITATIONS
1	Thickness and Layer Stacking Order Effects on Complex Optical Conductivity and Exciton Strength of Few-Layer Graphene: Implications for Optical Modulators and Photodetectors. ACS Applied Nano Materials, 2022, 5, 1864-1872.	5.0	7
2	Thickness Scaling Effects on the Complex Optical Conductivity of Few-Layer WSe ₂ Investigated by Spectroscopic Ellipsometry. Advanced Photonics Research, 2022, 3, .	3.6	4
3	Concentric ring structure on the front surface of fused silica induced by a focused femtosecond pulse laser. Precision Engineering, 2022, 74, 242-246.	3.4	0
4	Machine learning aided solution to the inverse problem in optical scatterometry. Measurement: Journal of the International Measurement Confederation, 2022, 191, 110811.	5.0	12
5	Optical wafer defect inspection at the 10 nm technology node and beyond. International Journal of Extreme Manufacturing, 2022, 4, 032001.	12.7	25
6	Superachromatic polarization modulator for stable and complete polarization measurement over an ultra-wide spectral range. Optics Express, 2022, 30, 15113.	3.4	6
7	Nanopatterning Technologies of 2D Materials for Integrated Electronic and Optoelectronic Devices. Advanced Materials, 2022, 34, e2200734.	21.0	25
8	Optical and electronic anisotropy of a 2D semiconductor SiP. Nano Research, 2022, 15, 8579-8586.	10.4	8
9	Femtosecond laser induced damaging inside fused silica detected by a single-pulse ultrafast measurement system. Optics Express, 2022, 30, 26111.	3.4	4
10	Characterization of pixelated nanogratings in 3D holographic display by an imaging Mueller matrix ellipsometry. Optics Letters, 2022, 47, 3580.	3.3	4
11	Determination of Dielectric Functions and Exciton Oscillator Strength of Two-Dimensional Hybrid Perovskites. , 2021, 3, 148-159.		47
12	Effective medium approximation based interpretation for Mueller matrix spectra of polydimethylsiloxane gratings. Journal of Optics (United Kingdom), 2021, 23, 025403.	2.2	0
13	Molecular Understanding of Electrochemical-Mechanical Responses in Carbon-Coated Silicon Nanotubes during Lithiation. Nanomaterials, 2021, 11, 564.	4.1	7
14	Complete Dielectric Tensor and Giant Optical Anisotropy in Quasi-One-Dimensional ZrTe ₅ . , 2021, 3, 525-534.		22
15	Birefringence and Dichroism in Quasi-1D Transition Metal Trichalcogenides: Direct Experimental Investigation. Small, 2021, 17, e2100457.	10.0	17
16	2D Niobium-Doped MoS ₂ : Tuning the Exciton Transitions and Potential Applications. ACS Applied Electronic Materials, 2021, 3, 2564-2572.	4.3	12
17	Beam collapse and refractive index changes inside fused silica induced by loosely focused femtosecond laser. Journal of Optics (United Kingdom), 2021, 23, 075402.	2.2	0
18	Complex optical conductivity of Bi ₂ Se ₃ thin film: Approaching two-dimensional limit. Applied Physics Letters, 2021, 118, .	3.3	10

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19	Diffraction based single pulse measurement of air ionization dynamics induced by femtosecond laser. Optics Express, 2021, 29, 18601.	3.4	5
20	Effect of nitrogen content on optical properties of transparent $\hat{\Gamma}^3$ -AlON polycrystalline ceramics. Journal of the European Ceramic Society, 2021, 41, 4319-4326.	5.7	15
21	Error analysis of a photoelastic-modulated Mueller matrix ellipsometer. , 2021, , .		0
22	Reconstruction of finite deep sub-wavelength nanostructures by Mueller-matrix scattered-field microscopy. Optics Express, 2021, 29, 32158.	3.4	7
23	Strong Second- and Third-Harmonic Generation in 1D Chiral Hybrid Bismuth Halides. Journal of the American Chemical Society, 2021, 143, 16095-16104.	13.7	74
24	An imbalance aware lithography hotspot detection method based on HDAM and pre-trained GoogLeNet. Measurement Science and Technology, 2021, 32, 125008.	2.6	6
25	Imaging Mueller matrix ellipsometry with sub-micron resolution based on back focal plane scanning. Optics Express, 2021, 29, 32712.	3.4	20
26	Eigenvalue calibration method for dual rotating-compensator Mueller matrix polarimetry. Optics Letters, 2021, 46, 4618.	3.3	11
27	Unsupervised learning polarimetric underwater image recovery under nonuniform optical fields. Applied Optics, 2021, 60, 8198.	1.8	8
28	X-ray scatterometry using deep learning. , 2021, , .		1
29	Optical Model and Optimization for Coherent-Incoherent Hybrid Organic Solar Cells with Nanostructures. Nanomaterials, 2021, 11, 3187.	4.1	2
30	An analytical method to determine the complex refractive index of an ultra-thin film by ellipsometry. Applied Surface Science, 2020, 507, 145091.	6.1	18
31	A novel spinel-type $Mg_{0.55}Al_{2.36}O_{3.81}Ni_{0.19}$ transparent ceramic with infrared transmittance range comparable to c-plane sapphire. Scripta Materialia, 2020, 178, 428-432.	5.2	25
32	Ultrathin Polymer Nanofibrils for Solar-Blind Deep Ultraviolet Light Photodetectors Application. Nano Letters, 2020, 20, 644-651.	9.1	38
33	Layer-dependent dielectric permittivity of topological insulator Bi_2Se_3 thin films. Applied Surface Science, 2020, 509, 144822.	6.1	29
34	Remote Absolute Roll-Angle Measurement in Range of 180° Based on Polarization Modulation. Nanomanufacturing and Metrology, 2020, 3, 228-235.	3.0	7
35	A Brewster incidence method for shocked dynamic metrology of transparent materials and its error evaluation. AIP Advances, 2020, 10, 105203.	1.3	0
36	Giant Gate-Tunability of Complex Refractive Index in Semiconducting Carbon Nanotubes. ACS Photonics, 2020, 7, 2896-2905.	6.6	16

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37	Dynamic modulation performance of ferroelectric liquid crystal polarization rotators and Mueller matrix polarimeter optimization. <i>Frontiers of Mechanical Engineering</i> , 2020, 15, 256-264.	4.3	3
38	Investigation of Spatial Chirp Induced by Misalignments in a Parallel Grating Pair Pulse Stretcher. <i>Applied Sciences (Switzerland)</i> , 2020, 10, 1584.	2.5	10
39	Annealing temperature dependence of optical and structural properties of Cu films. <i>Physical Review B</i> , 2020, 101, .	3.2	0
40	Thickness dependent native oxidation kinetics observation and prediction for Cu films using spectroscopic ellipsometry. <i>Applied Surface Science</i> , 2020, 518, 146236.	6.1	8
41	Multiobjective optimization for target design in diffraction-based overlay metrology. <i>Applied Optics</i> , 2020, 59, 2897.	1.8	5
42	Performance optimization of tandem organic solar cells at varying incident angles based on optical analysis method. <i>Optics Express</i> , 2020, 28, 2381.	3.4	8
43	On the limits of low-numerical-aperture imaging scatterometry. <i>Optics Express</i> , 2020, 28, 8445.	3.4	6
44	High-speed Mueller matrix ellipsometer with microsecond temporal resolution. <i>Optics Express</i> , 2020, 28, 10873.	3.4	18
45	Attitude metrology based on the field-of-view effect of birefringence using high-speed polarimetry. <i>Optics Letters</i> , 2020, 45, 2074.	3.3	5
46	Fast reconstruction of the aberrated scanning lithographic image by a quadratic imaging model and an integral transfer function. <i>Applied Optics</i> , 2020, 59, 4708.	1.8	0
47	Nonuniform depolarization properties of typical nanostructures and potential applications. <i>Optics Letters</i> , 2020, 45, 1910.	3.3	6
48	Multi-objective collaborative optimization strategy for efficiency and chromaticity of stratified OLEDs based on an optical simulation method and sensitivity analysis. <i>Optics Express</i> , 2020, 28, 27532.	3.4	3
49	Optical Scatterometry for Nanostructure Metrology. <i>Precision Manufacturing</i> , 2019, , 477-513.	0.1	4
50	Dependence-Analysis-Based Data-Refinement in Optical Scatterometry for Fast Nanostructure Reconstruction. <i>Applied Sciences (Switzerland)</i> , 2019, 9, 4091.	2.5	4
51	Strain-optical behavior of polyethylene terephthalate film during uniaxial stretching investigated by Mueller matrix ellipsometry. <i>Polymer</i> , 2019, 182, 121842.	3.8	8
52	Valid corollaries of polarization-separated color attributes for a multi-layer dielectric structure. <i>Physica Scripta</i> , 2019, 94, 115007.	2.5	0
53	Complex Optical Conductivity of Two-Dimensional MoS ₂ : A Striking Layer Dependency. <i>Journal of Physical Chemistry Letters</i> , 2019, 10, 6246-6252.	4.6	35
54	Beyond the Thermal Equilibrium Limit of Ammonia Synthesis with Dual Temperature Zone Catalyst Powered by Solar Light. <i>CheM</i> , 2019, 5, 2702-2717.	11.7	91

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55	Layer-dependent dielectric and optical properties of centimeter-scale 2D WSe ₂ : evolution from a single layer to few layers. <i>Nanoscale</i> , 2019, 11, 22762-22771.	5.6	55
56	Optical Scatterometry for Nanostructure Metrology. <i>Precision Manufacturing</i> , 2019, , 1-37.	0.1	1
57	Highly transparent Mg _{0.27} Al _{2.58} O _{3.73} N _{0.27} ceramic fabricated by aqueous gelcasting, pressureless sintering, and post-HIP. <i>Journal of the American Ceramic Society</i> , 2019, 102, 6507-6516.	3.8	16
58	Dynamic characteristics of nematic liquid crystal variable retarders investigated by a high-speed polarimetry. <i>Journal of Optics (United Kingdom)</i> , 2019, 21, 065605.	2.2	6
59	Characterization of Volume Gratings Based on Distributed Dielectric Constant Model Using Mueller Matrix Ellipsometry. <i>Applied Sciences (Switzerland)</i> , 2019, 9, 698.	2.5	6
60	Evaporable Glass-State Molecule-Assisted Transfer of Clean and Intact Graphene onto Arbitrary Substrates. <i>ACS Applied Materials & Interfaces</i> , 2019, 11, 16272-16279.	8.0	20
61	Flexible Perovskite Solar Cells via Surface-Confined Silver Nanoparticles on Transparent Polyimide Substrates. <i>Polymers</i> , 2019, 11, 427.	4.5	22
62	Proof of principle of an optical Stokes absolute roll-angle sensor with ultra-large measuring range. <i>Sensors and Actuators A: Physical</i> , 2019, 291, 144-149.	4.1	8
63	Characterization of dielectric function for metallic thin films based on ellipsometric parameters and reflectivity. <i>Physica Scripta</i> , 2019, 94, 085802.	2.5	10
64	Optical Analysis for Semitransparent Organic Solar Cells. <i>Solar Rrl</i> , 2019, 3, 1800270.	5.8	62
65	Nondestructive investigation on the nanocomposite ordering upon holography using Mueller matrix ellipsometry. <i>European Polymer Journal</i> , 2019, 110, 123-129.	5.4	8
66	Calibration of polarization effect of a high-numerical-aperture objective lens with Mueller matrix polarimetry. <i>Measurement Science and Technology</i> , 2019, 30, 025201.	2.6	15
67	Layer-Dependent Dielectric Function of Wafer-Scale 2D MoS ₂ . <i>Advanced Optical Materials</i> , 2019, 7, 1801250.	7.3	58
68	Characterization of a liquid crystal variable retarder by Mueller matrix ellipsometry. , 2019, , .		2
69	Simulation method for study on outcoupling characteristics of stratified anisotropic OLEDs. <i>Optics Express</i> , 2019, 27, A1014.	3.4	16
70	Wide field-of-view angle linear retarder with an ultra-flat retardance response. <i>Optics Letters</i> , 2019, 44, 3026.	3.3	5
71	Inverse outcoupling for emitter features of stratified anisotropic OLED structures. , 2019, , .		0
72	Efficiency optimization of tandem organic solar cells under oblique incidence based on optical analysis method. , 2019, , .		0

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73	In-line wavefront aberration adjustment of a projection lens for a lithographic tool using the dominant mode method. <i>Applied Optics</i> , 2019, 58, 4176.	1.8	1
74	Vectorial modeling for the image formation of a high-numerical-aperture Mueller-matrix ellipsometer. , 2019, , .		0
75	Broadband optical properties of graphene and HOPG investigated by spectroscopic Mueller matrix ellipsometry. <i>Applied Surface Science</i> , 2018, 439, 1079-1087.	6.1	67
76	2D Layered Materials-Based van der Waals Heterostructures for Optoelectronics. <i>Advanced Functional Materials</i> , 2018, 28, 1706587.	14.9	279
77	Highly Efficient Tandem Organic Solar Cell Enabled by Environmentally Friendly Solvent Processed Polymeric Interconnecting Layer. <i>Advanced Energy Materials</i> , 2018, 8, 1703180.	19.5	44
78	Probing optimal measurement configuration for optical scatterometry by the multi-objective genetic algorithm. <i>Measurement Science and Technology</i> , 2018, 29, 045014.	2.6	7
79	Preparation of transparent MgO·1.8Al ₂ O ₃ spinel ceramics by aqueous gelcasting, presintering and hot isostatic pressing. <i>Journal of the European Ceramic Society</i> , 2018, 38, 4057-4063.	5.7	25
80	Study of the retardance of a birefringent waveplate at tilt incidence by Mueller matrix ellipsometer. <i>Journal of Optics (United Kingdom)</i> , 2018, 20, 015401.	2.2	23
81	Efficient light-driven CO ₂ hydrogenation on Ru/CeO ₂ catalysts. <i>Catalysis Science and Technology</i> , 2018, 8, 6503-6510.	4.1	18
82	Characterization of beam splitters in the calibration of a six-channel Stokes polarimeter. <i>Journal of Optics (United Kingdom)</i> , 2018, 20, 125606.	2.2	11
83	Metrology of Nanostructures by Tomographic Mueller-Matrix Scatterometry. <i>Applied Sciences (Switzerland)</i> , 2018, 8, 2583.	2.5	9
84	24.1% External Quantum Efficiency of Flexible Quantum Dot Light-Emitting Diodes by Light Extraction of Silver Nanowire Transparent Electrodes. <i>Advanced Optical Materials</i> , 2018, 6, 1800347.	7.3	51
85	All-dielectric metasurface-based roll-angle sensor. <i>Sensors and Actuators A: Physical</i> , 2018, 279, 509-517.	4.1	14
86	Robust overlay metrology by Mueller matrix ellipsometry with a differential calculus. , 2018, , .		0
87	Development of a tomographic Mueller-matrix scatterometer for nanostructure metrology. <i>Review of Scientific Instruments</i> , 2018, 89, 073702.	1.3	11
88	Ultra Uniform Pb _{0.865} La _{0.09} (Zr _{0.65} Ti _{0.35})O ₃ Thin Films with Tunable Optical Properties Fabricated via Pulsed Laser Deposition. <i>Materials</i> , 2018, 11, 525.	2.9	1
89	Overcoming Space-Charge Effect for Efficient Thick-Film Non-Fullerene Organic Solar Cells. <i>Advanced Energy Materials</i> , 2018, 8, 1801609.	19.5	62
90	To improve the efficiency of thermally activated delayed fluorescence OLEDs by controlling the horizontal orientation through optimizing stereoscopic and linear structures of indolocarbazole isomers. <i>Journal of Materials Chemistry C</i> , 2018, 6, 5812-5820.	5.5	49

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91	Measurement configuration optimization for dynamic metrology using Stokes polarimetry. <i>Measurement Science and Technology</i> , 2018, 29, 054010.	2.6	6
92	Comprehensive characterization of a general composite waveplate by spectroscopic Mueller matrix polarimetry. <i>Optics Express</i> , 2018, 26, 25408.	3.4	24
93	Spectroscopic ellipsometry and X-ray diffraction studies on Si _{1-x} Ge _x /Si epilayers and superlattices. <i>Applied Surface Science</i> , 2017, 421, 748-754.	6.1	2
94	Polarization multiplexed all-dielectric metasurfaces for wavefront manipulation in a transmission mode. <i>Journal of Optics (United Kingdom)</i> , 2017, 19, 105102.	2.2	3
95	Robust overlay metrology with differential Mueller matrix calculus. <i>Optics Express</i> , 2017, 25, 8491.	3.4	6
96	Reduced-basis boundary element method for fast electromagnetic field computation. <i>Journal of the Optical Society of America A: Optics and Image Science, and Vision</i> , 2017, 34, 2231.	1.5	3
97	Mechanical property of Cu-Sn-Ni intermetallics in the full intermetallic micro-joints formed with transient liquid phase soldering. , 2017, , .		1
98	High-performance Polymer Tandem Solar Cells Employing a New n-type Conjugated Polymer as an Interconnecting Layer. <i>Advanced Materials</i> , 2016, 28, 4817-4823.	21.0	156
99	Characterization of curved surface layer by Mueller matrix ellipsometry. <i>Journal of Vacuum Science and Technology B: Nanotechnology and Microelectronics</i> , 2016, 34, .	1.2	11
100	Development of a spectroscopic Mueller matrix imaging ellipsometer for nanostructure metrology. <i>Review of Scientific Instruments</i> , 2016, 87, 053707.	1.3	21
101	Nondestructive analysis of lithographic patterns with natural line edge roughness from Mueller matrix ellipsometric data. <i>Applied Surface Science</i> , 2016, 388, 524-530.	6.1	9
102	Accurate alignment of optical axes of a biplate using a spectroscopic Mueller matrix ellipsometer. <i>Applied Optics</i> , 2016, 55, 3935.	2.1	16
103	Application of measurement configuration optimization for accurate metrology of sub-wavelength dimensions in multilayer gratings using optical scatterometry. <i>Applied Optics</i> , 2016, 55, 6844.	2.1	9
104	Optimal design of wide-view-angle waveplate used for polarimetric diagnosis of lithography system. , 2016, , .		1
105	Incorporating photomask shape uncertainty in computational lithography. , 2016, , .		1
106	Optimal broadband Mueller matrix ellipsometer using multi-waveplates with flexibly oriented axes. <i>Journal of Optics (United Kingdom)</i> , 2016, 18, 025702.	2.2	52
107	Depolarization artifacts in dual rotating-compensator Mueller matrix ellipsometry. <i>Journal of Optics (United Kingdom)</i> , 2016, 18, 055701.	2.2	22
108	Generalized measurement configuration optimization for accurate reconstruction of periodic nanostructures using optical scatterometry. , 2016, , .		2

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109	Improved nanostructure reconstruction by performing data refinement in optical scatterometry. <i>Journal of Optics (United Kingdom)</i> , 2016, 18, 015605.	2.2	5
110	Direct Tailoring the Si Substrate for Antireflection via Random Nanohole Nanoimprint. <i>Journal of Nanoscience and Nanotechnology</i> , 2015, 15, 1297-1303.	0.9	5
111	Towards understanding the detection of profile asymmetry from Mueller matrix differential decomposition. <i>Journal of Applied Physics</i> , 2015, 118, .	2.5	12
112	Fast and accurate solution of inverse problem in optical scatterometry using heuristic search and robust correction. <i>Journal of Vacuum Science and Technology B: Nanotechnology and Microelectronics</i> , 2015, 33, .	1.2	2
113	Sparse nonlinear inverse imaging for shot count reduction in inverse lithography. <i>Optics Express</i> , 2015, 23, 26919.	3.4	4
114	Data refinement for robust solution to the inverse problem in optical scatterometry. <i>Proceedings of SPIE</i> , 2015, , .	0.8	0
115	Measurement errors induced by axis tilt of biplates in dual-rotating compensator Mueller matrix ellipsometers. , 2015, , .		2
116	Development of a broadband Mueller matrix ellipsometer as a powerful tool for nanostructure metrology. <i>Thin Solid Films</i> , 2015, 584, 176-185.	1.8	121
117	Improved deep-etched multilayer grating reconstruction by considering etching anisotropy and abnormal errors in optical scatterometry. <i>Optics Letters</i> , 2015, 40, 471.	3.3	14
118	Mueller matrix imaging ellipsometry for nanostructure metrology. <i>Optics Express</i> , 2015, 23, 17316.	3.4	48
119	Ellipsometry study on Pd thin film grown by atomic layer deposition with Maxwell's Garnett effective medium approximation model. <i>Thin Solid Films</i> , 2015, 593, 144-149.	1.8	7
120	Calibration of misalignment errors in composite waveplates using Mueller matrix ellipsometry. <i>Applied Optics</i> , 2015, 54, 684.	1.8	25
121	Correction of depolarization effect in Mueller matrix ellipsometry with polar decomposition method. <i>Proceedings of SPIE</i> , 2015, , .	0.8	1
122	Cascadic multigrid algorithm for robust inverse mask synthesis in optical lithography. <i>Journal of Micro/ Nanolithography, MEMS, and MOEMS</i> , 2014, 13, 023003.	0.9	10
123	Mueller matrix ellipsometric detection of profile asymmetry in nanoimprinted grating structures. <i>Journal of Applied Physics</i> , 2014, 116, 194305.	2.5	19
124	Robust and efficient inverse mask synthesis with basis function representation. <i>Journal of the Optical Society of America A: Optics and Image Science, and Vision</i> , 2014, 31, B1.	1.5	12
125	Efficient source mask optimization with Zernike polynomial functions for source representation. <i>Optics Express</i> , 2014, 22, 3924.	3.4	19
126	Illumination source optimization in optical lithography via derivative-free optimization. <i>Journal of the Optical Society of America A: Optics and Image Science, and Vision</i> , 2014, 31, B19.	1.5	10

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127	Accurate characterization of nanoimprinted resist patterns using Mueller matrix ellipsometry. Optics Express, 2014, 22, 15165.	3.4	35
128	Robust solution to the inverse problem in optical scatterometry. Optics Express, 2014, 22, 22031.	3.4	25
129	Efficient representation of mask transmittance functions for vectorial lithography simulations. Journal of the Optical Society of America A: Optics and Image Science, and Vision, 2014, 31, B10.	1.5	2
130	Effect of cation and anion defects on the resistive switching polarity of ZnO x thin films. Applied Physics A: Materials Science and Processing, 2014, 114, 847-852.	2.3	6
131	Porous Light-Emitting Diodes With Patterned Sapphire Substrates Realized by High-Voltage Self-Growth and Soft UV Nanoimprint Processes. Journal of Lightwave Technology, 2014, 32, 326-332.	4.6	21
132	Synthesis of a nanowire self-assembled hierarchical ZnCo ₂ O ₄ shell/Ni current collector core as binder-free anodes for high-performance Li-ion batteries. Journal of Materials Chemistry A, 2014, 2, 3741-3748.	10.3	91
133	A single-image method of aberration retrieval for imaging systems under partially coherent illumination. Journal of Optics (United Kingdom), 2014, 16, 072001.	2.2	4
134	Formulation of error propagation and estimation in grating reconstruction by a dual-rotating compensator Mueller matrix polarimeter. Thin Solid Films, 2014, 571, 653-659.	1.8	27
135	Determination of an optimal measurement configuration in optical scatterometry using global sensitivity analysis. Thin Solid Films, 2014, 562, 16-23.	1.8	20
136	Effective simulation for robust inverse lithography using convolution-variation separation method. Proceedings of SPIE, 2014, , .	0.8	0
137	(Invited) Mueller Matrix Polarimetry: A Powerful Tool for Nanostructure Metrology. ECS Transactions, 2014, 60, 237-242.	0.5	12
138	Nondestructive detection of nano grating by generalized ellipsometer. Wuli Xuebao/Acta Physica Sinica, 2014, 63, 039101.	0.5	3
139	Accurate measurement of templates and imprinted grating structures using Mueller matrix ellipsometry. Wuli Xuebao/Acta Physica Sinica, 2014, 63, 180701.	0.5	2
140	Photonic crystal structures on nonflat surfaces fabricated by dry lift-off soft UV nanoimprint lithography. Journal of Micromechanics and Microengineering, 2013, 23, 125002.	2.6	2
141	Optimization of stresses in a local region for the maximization of sensitivity and minimization of cross-sensitivity of piezoresistive sensors. Structural and Multidisciplinary Optimization, 2013, 48, 927-938.	3.5	10
142	Improved measurement accuracy in optical scatterometry using fitting error interpolation based library search. Measurement: Journal of the International Measurement Confederation, 2013, 46, 2638-2646.	5.0	20
143	Fabrication of the similar porous alumina silicon template for soft UV nanoimprint lithography. Applied Surface Science, 2013, 276, 363-368.	6.1	21
144	Shape and topology optimization for tailoring stress in a local region to enhance performance of piezoresistive sensors. Computers and Structures, 2013, 114-115, 98-105.	4.4	30

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145	Pixel-based inverse lithography using a mask filtering technique. Proceedings of SPIE, 2013, , .	0.8	3
146	Convolution-variation separation method for efficient modeling of optical lithography. Optics Letters, 2013, 38, 2168.	3.3	7
147	Numerical analysis of transmission efficiency for parabolic optical fiber nano-probe. Optics Express, 2013, 21, 28103.	3.4	1
148	Improved measurement accuracy in optical scatterometry using correction-based library search. Applied Optics, 2013, 52, 6726.	1.8	28
149	Efficient source and mask optimization with augmented Lagrangian methods in optical lithography. Optics Express, 2013, 21, 8076.	3.4	55
150	Level-set-based inverse lithography for mask synthesis using the conjugate gradient and an optimal time step. Journal of Vacuum Science and Technology B:Nanotechnology and Microelectronics, 2013, 31, .	1.2	36
151	Mask-filtering-based inverse lithography. Journal of Micro/ Nanolithography, MEMS, and MOEMS, 2013, 12, 043003.	0.9	15
152	Ellipsometry Study on Nanoparticles Grown by Atomic Layer Deposition. Materials Research Society Symposia Proceedings, 2013, 1548, 1.	0.1	1
153	Identification and reconstruction of diffraction structures in optical scatterometry using support vector machine method. Journal of Micro/ Nanolithography, MEMS, and MOEMS, 2013, 12, 013004.	0.9	17
154	Depolarization effects from nanoimprinted grating structures as measured by Mueller matrix polarimetry. Applied Physics Letters, 2013, 103, .	3.3	29
155	Computational metrology for nanomanufacturing. Proceedings of SPIE, 2013, , .	0.8	2
156	Fabrication and Properties of Dual-Level Hierarchical Structures Mimicking Gecko Foot Hairs. Journal of Nanoscience and Nanotechnology, 2013, 13, 781-786.	0.9	7
157	Optimal configuration for the dual rotating-compensator Mueller matrix ellipsometer. , 2013, , .		6
158	Measurement configuration optimization for accurate grating reconstruction by Mueller matrix polarimetry. Journal of Micro/ Nanolithography, MEMS, and MOEMS, 2013, 12, 033013.	0.9	30
159	The fabrication of the antireflective periodic nano-array structure on Si surface using nanoimprint lithography and the study on its properties. Wuli Xuebao/Acta Physica Sinica, 2013, 62, 168102.	0.5	2
160	Metal-Catalyst-Free Synthesis and Characterization of Single-Crystalline Silicon Oxynitride Nanowires. Journal of Nanomaterials, 2012, 2012, 1-8.	2.7	3
161	Fast aerial image simulations for partially coherent systems by transmission cross coefficient decomposition with analytical kernels. Journal of Vacuum Science and Technology B:Nanotechnology and Microelectronics, 2012, 30, .	1.2	10
162	Tailoring diffraction-induced light distribution toward controllable fabrication of suspended C-MEMS. Optics Express, 2012, 20, 17126.	3.4	10

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163	Kernel-based parametric analytical model of source intensity distributions in lithographic tools. Applied Optics, 2012, 51, 1479.	1.8	1
164	Iterative method for in situ measurement of lens aberrations in lithographic tools using CTC-based quadratic aberration model. Optics Express, 2012, 20, 14272.	3.4	8
165	Comment on "Three-dimensional imaging of a phase object from a single sample orientation using an optical laser". Physical Review B, 2012, 86, .	3.2	2
166	In-situ measurement of lens aberrations in lithographic tools using CTC-based quadratic aberration model. Proceedings of SPIE, 2012, , .	0.8	0
167	Pyrolysis-assisted graphene exfoliation from graphite particles deposited on photoresist pillars. , 2012, , .		0
168	Concentration gradient induced morphology evolution of silica nanostructure growth on photoresist-derived carbon micropatterns. Nanoscale Research Letters, 2012, 7, 496.	5.7	1
169	Estimation of the convergence order of rigorous coupled-wave analysis for binary gratings in optical critical dimension metrology. Optical Engineering, 2012, 51, 081504.	1.0	35
170	A level set solution to the stress-based structural shape and topology optimization. Computers and Structures, 2012, 90-91, 55-64.	4.4	167
171	Fabrication of high aspect ratio microfiber arrays that mimic gecko foot hairs. Science Bulletin, 2012, 57, 404-408.	1.7	5
172	Computational lithography and computational metrology for nanomanufacturing. , 2011, , .		3
173	Fitting-determined formulation of effective medium approximation for 3D trench structures in model-based infrared reflectometry. Journal of the Optical Society of America A: Optics and Image Science, and Vision, 2011, 28, 263.	1.5	10
174	Fast algorithm for quadratic aberration model based on cross triple correlation. Proceedings of SPIE, 2011, , .	0.8	0
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